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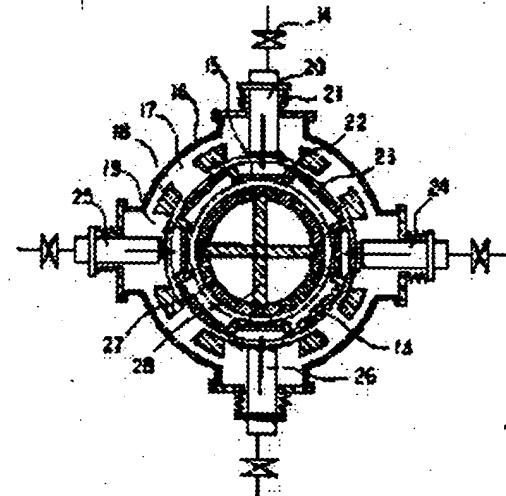
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(54) ATOMIC LAYER EPITAXY APPARATUS

(57)Abstract:

PURPOSE: To reduce a volume of a vacuum chamber, to extremely effectively conduct an atomic layer epitaxy and to improve reliability.

CONSTITUTION: Gas cells 20, 24, 26, 25 are disposed in a vacuum chamber 16. Shapes of discharge ports of the cells 20, 24, 26, 25 are formed in a rectangular shape in which its long side is at least longer than a diameter of a substrate 15. A gas diffusion plate is provided from gas introducing tubes of the cells 20, 24, 26, 25 to the ports. A plurality of the substrates 15 are rotatably moved perpendicularly to the diffusing directions of the cells 20, 24, 26, 25 to alternately irradiate the substrates 15 with a plurality of types of the gases from the cells 20, 24, 26, 25, thereby repeating an atomic layer epitaxy.



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